

FIG. 1A

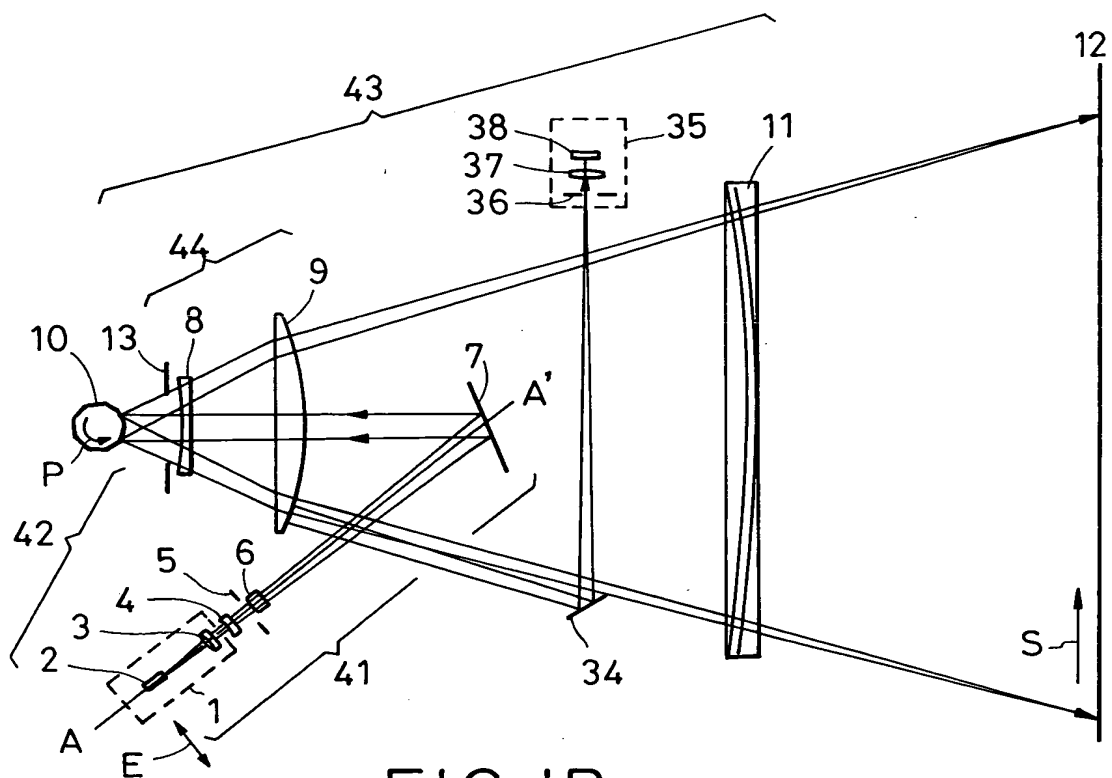


FIG. 1B

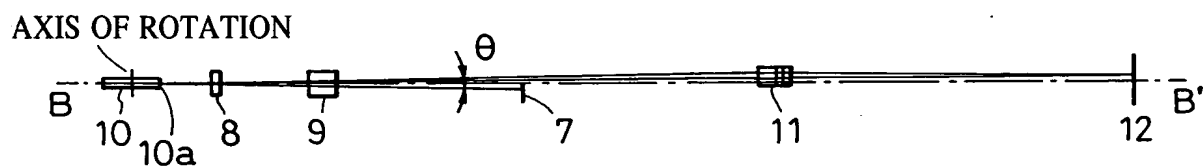


FIG. 1C

SECTION TAKEN ALONG LINE AA'

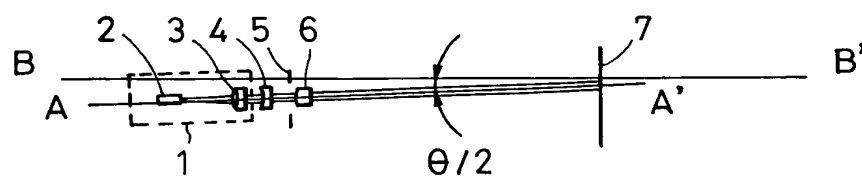
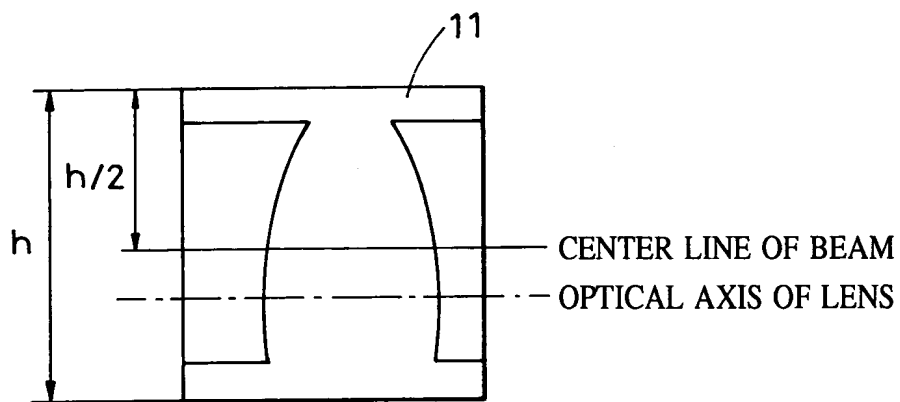


FIG. 2



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FIG. 3A

WITH SEMICONDUCTOR LASER CHIP NOT TILTED

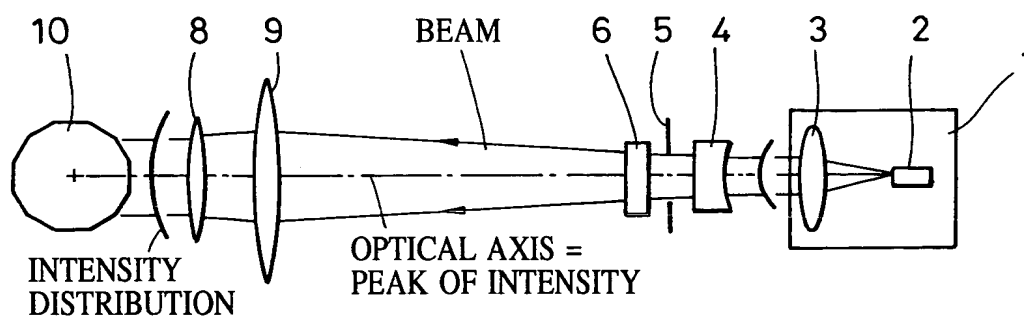


FIG. 3B

WITH SEMICONDUCTOR LASER CHIP TILTED

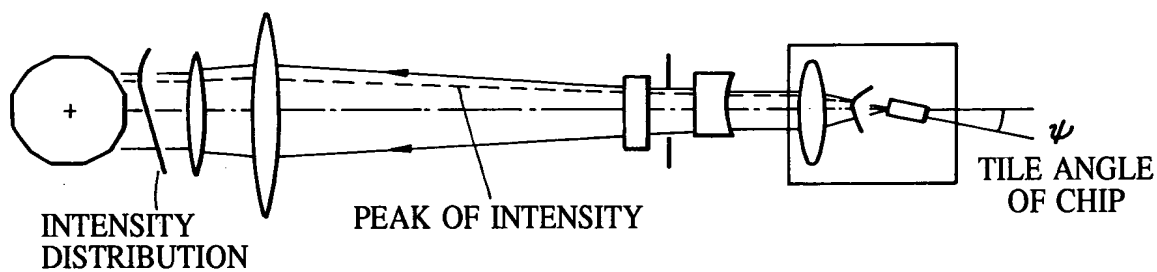


FIG. 3C

WITH SEMICONDUCTOR LASER CHIP SHIFTED

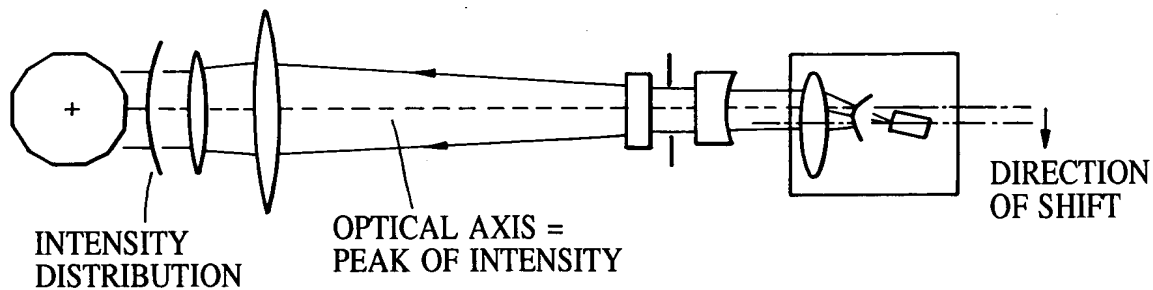


FIG. 4A

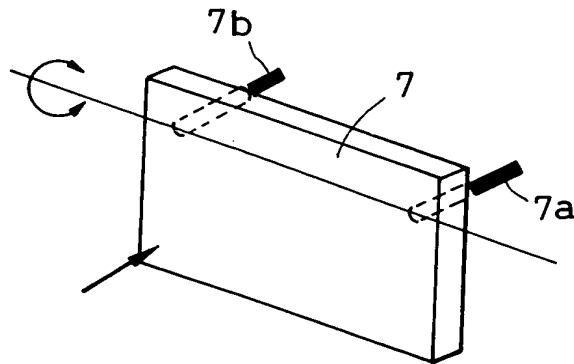


FIG. 4B

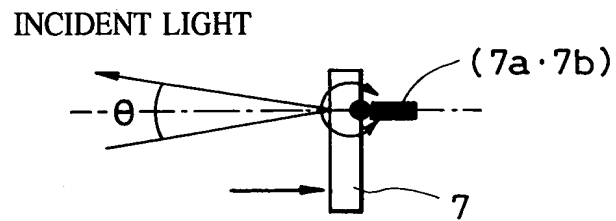


FIG. 4A

FIG. 5A

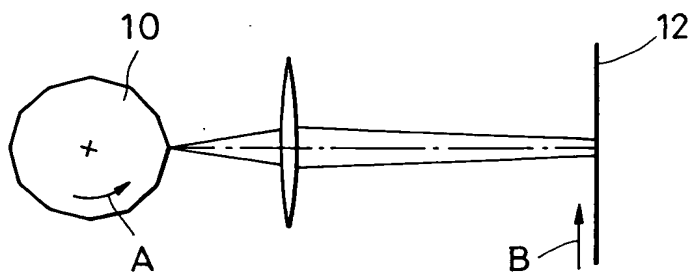


FIG. 5B

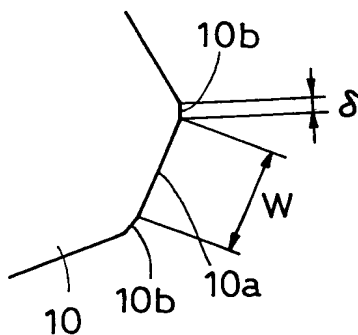


FIG. 6

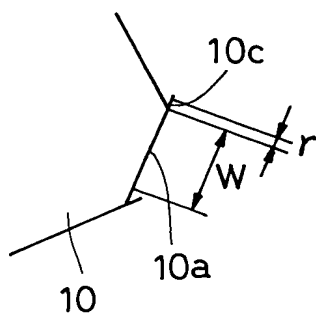


FIG. 5A

FIG. 7C

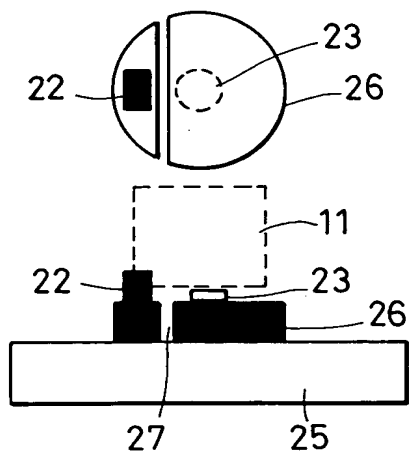


FIG. 8

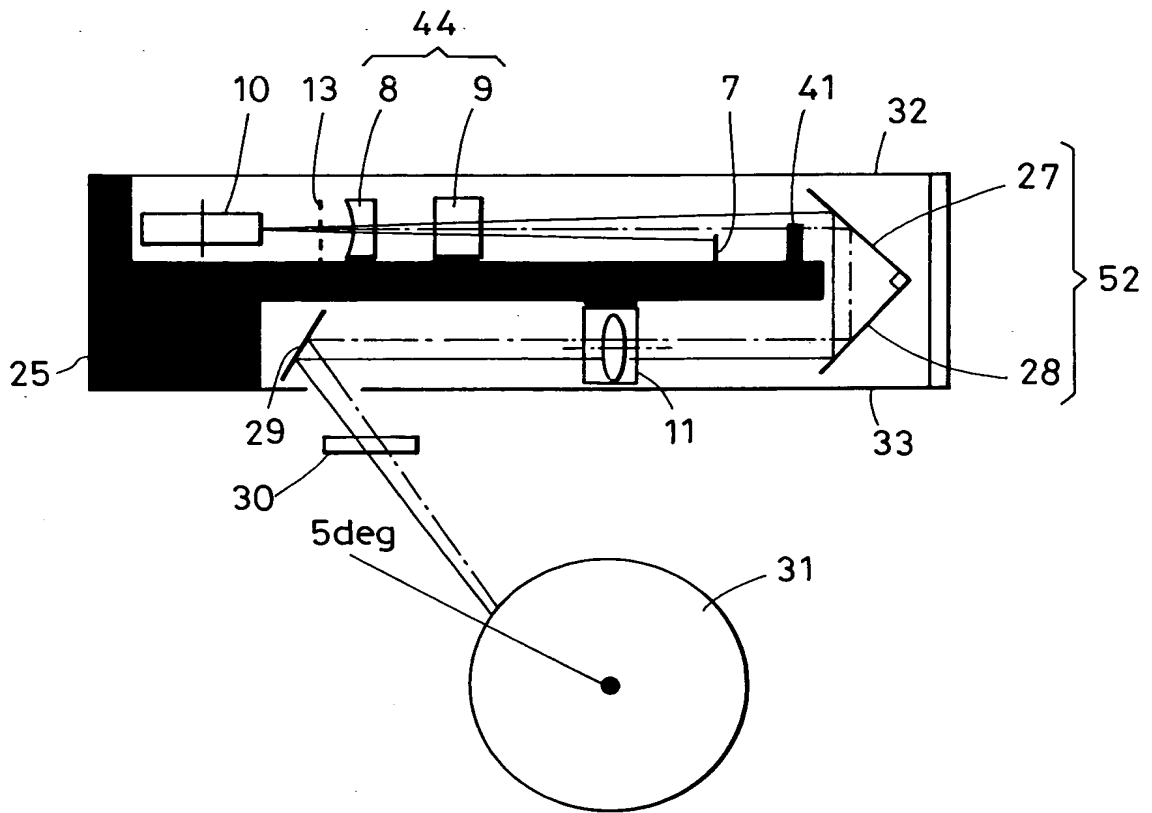


FIG. 8

FIG. 9A

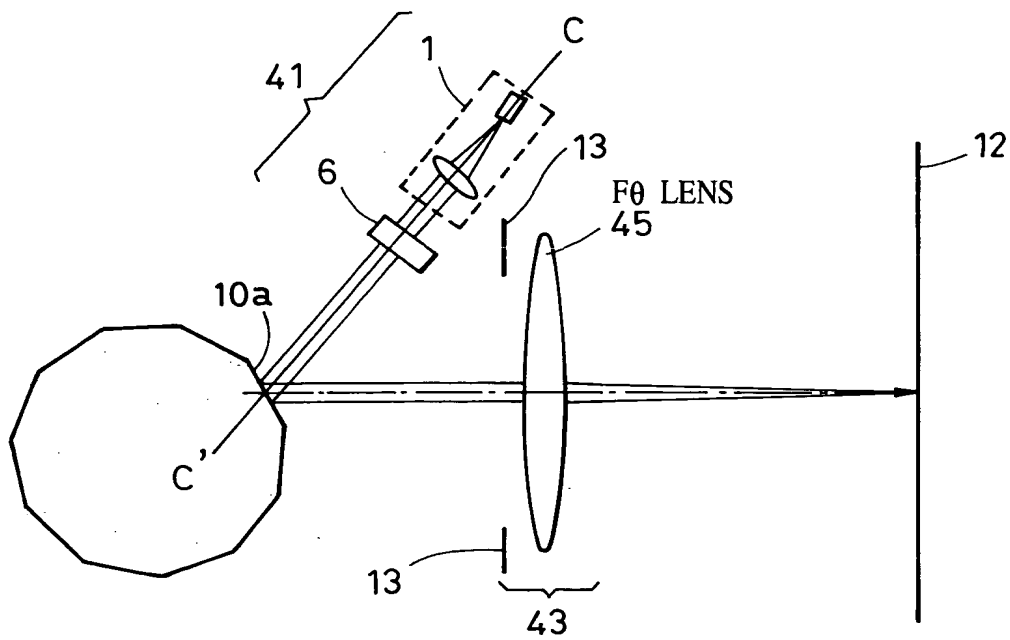


FIG. 9B

SECTION IN SUB-SCAN OPERATION TAKEN ALONG LINE CC'

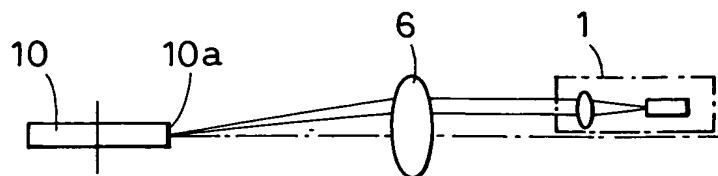




FIG. 10

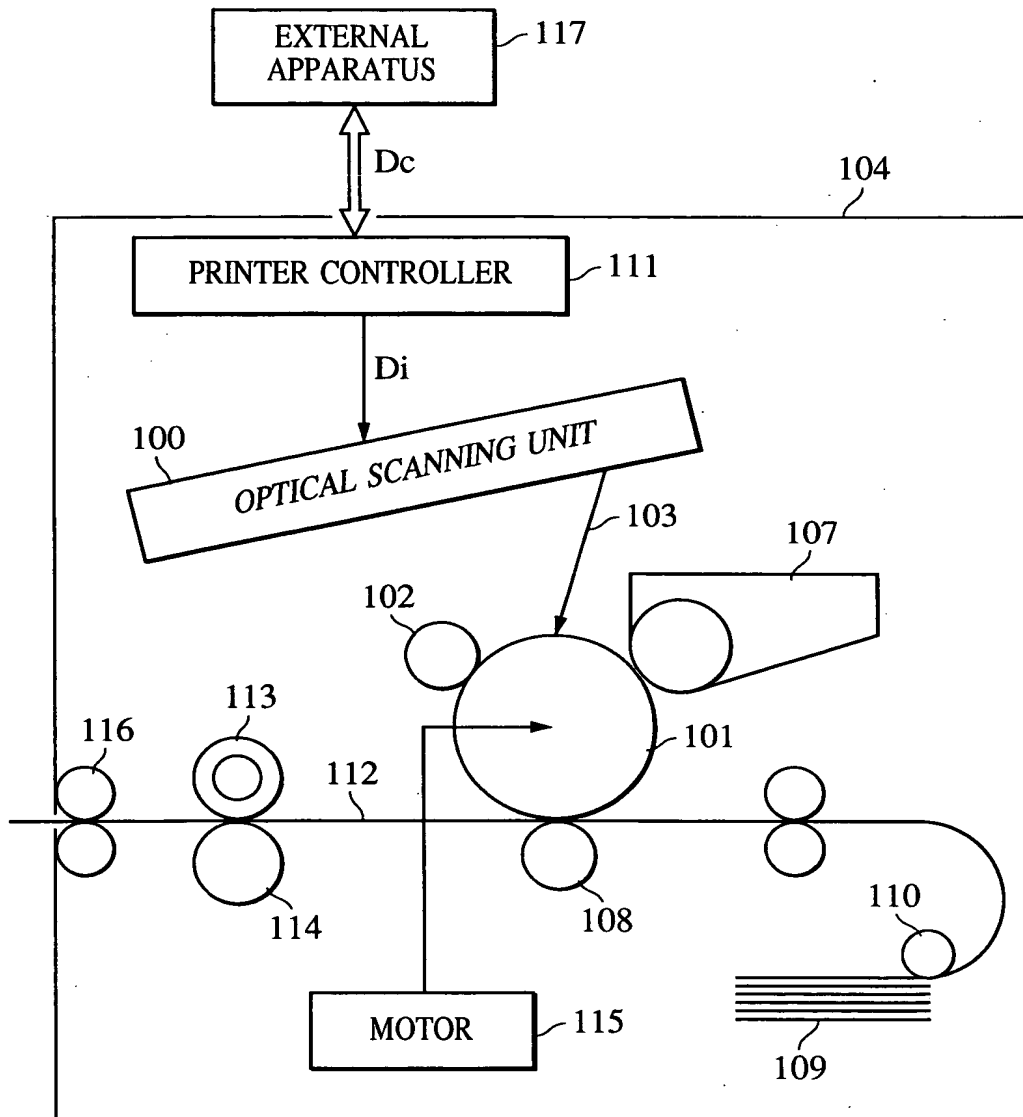


FIG. 10

FIG. 11

